

Instructions:

Seat Number _____

1. Do your own work. DO NOT REMOVE THE STAPLE ON THIS EXAM.
2. You may use a legal copy of the text by Massobrio and Antognetti. You may write notes in your text. You may NOT pass a book or note sheet to another student. You may NOT use class notes or previously solved problems.
3. Calculator allowed. You may NOT share a calculator with another student.
4. Where values or equations are given on this cover sheet, use them in lieu of any other source. If a value is not given, explicitly state definitions and assumptions that you use.
5. Where possible, calculate parameters rather than read them from a graph.
6. Do all work in the spaces provided on this exam paper. If you write on the back of a sheet, make the notation "PTO" in your solution in order to assure that material written on the back of the page is evaluated for a grade. AN EXTRA BLANK SHEET IS ATTACHED AT THE BACK OF THE EXAM.
7. Show all calculations, making numerical substitutions and giving numerical results where possible.
8. Write answers in space given.
9. Unless stated otherwise,

$$T = 300\text{K}, \quad V_t = 25.843 \text{ mV (to agree with M\&K } k \text{ and } q \text{ values)}$$

10. Unless otherwise stated, the material is silicon (300K) with

$$n_i = 1.45 \times 10^{10} \text{ cm}^{-3} \quad N_c = 2.8 \times 10^{19} \text{ cm}^{-3} \quad q\chi_{\text{Si}} = 4.05 \text{ eV}$$

$$E_{g,\text{Si}} = 1.124 \text{ eV} \quad N_v = 1.04 \times 10^{19} \text{ cm}^{-3}$$

11. For the work function of poly silicon, use

$$\phi_{n+} = \chi_{\text{Si}} = 4.05 \text{ V}$$

$$\phi_{p+} = \chi_{\text{Si}} + E_{g,\text{Si}}/q = 5.174 \text{ V}.$$

12. For minority carrier (either electrons or holes) lifetime in silicon, use the relationship

$$\tau_{\text{min}} = (4.5 \times 10^{-5} \text{ sec}) / (1 + N_i / 1 \times 10^{17} + (N_i / 5 \times 10^{17})^2),$$
 where N_i = the total impurity concentration in cm^{-3}

13. For holes in silicon doped primarily with boron, assume

$$\mu_p = \{470.5 \div [1 + (N_i \div 2.23 \times 10^{17})^{0.719}]\} + 44.9, \text{ in } \text{cm}^2/\text{V-sec}.$$

14. For electrons in silicon doped primarily with phosphorous, assume

$$\mu_n = \{1414 \div [1 + (N_i \div 9.2 \times 10^{16})^{0.711}]\} + 68.5, \text{ in } \text{cm}^2/\text{V-sec}.$$

15. For electrons in silicon doped primarily with arsenic, assume

$$\mu_n = \{1417 \div [1 + (N_i \div 9.68 \times 10^{16})^{0.68}]\} + 52.2, \text{ in } \text{cm}^2/\text{V-sec}.$$

(In 12 through 15, N_i = the total impurity concentration in n- or p-type material, compensated or not.)

(*13 may be used as an approximation for holes as minority carriers, likewise 14 for minority electrons.)

16. Metal gate work functions should be assumed to be

$$\phi_{\text{M,Al}} = 4.1 \text{ V for aluminum}, \quad \phi_{\text{M,Pt}} = 5.3 \text{ V for platinum}, \quad \phi_{\text{M,Au}} = 4.75 \text{ V for gold}$$

17. The electron affinity of SiO_2 is $\chi_{\text{SiO}_2} = 1.00 \text{ V}.$
18. Planck constant $h = 6.625 \times 10^{-34} \text{ J-s} = 4.135 \times 10^{-15} \text{ eV-s}, (1 \text{ eV} = 1.602 \times 10^{-19} \text{ Joule}).$
19. free electron mass $m_0 = 9.11 \times 10^{-28} \text{ g}.$
20. Boltzmann constant, $k = 1.38 \times 10^{-23} \text{ J/K}$
21. Electron charge, $q = 1.602 \times 10^{-19} \text{ Coulomb}$
22. Permittivity of free space, $\epsilon_0 = 8.854 \times 10^{-14} \text{ Fd/cm}$
23. Relative permittivity of silicon, $\epsilon_r = 11.7$
24. Relative permittivity of silicon dioxide, $\epsilon_{\text{rOx}} = 3.9$
25. The breakdown voltage of an abrupt (step) junction (asymmetrical or one-sided) diode with doping on the lightly doped side of N_B is $V_B = 60(E_g/1.1)^{3/2} (10^{16}/N_B)^{3/4} \text{ V}.$ The critical field for breakdown is modeled as $E_{\text{crit}} = (120 \text{ V} \cdot q N_B / (\epsilon_r \epsilon_0))^{1/2} \cdot (E_g/1.1)^{3/4} \cdot (10^{16}/N_B)^{3/8}$
26. Each part is worth [x] points, as given in the problem.

Notes:

The objective of this test will be to demonstrate that you know how to calculate device physics derived device properties for semiconductor material (primarily silicon) and the pn junction diode (including the static dc characteristics and the small- signal ac characterising). This is to include (but is not limited to):

carrier concentrations and Fermi energies

resistance and conductivity

mobility and diffusion coefficient

current density

capacitance

saturation current densities for a diode